L Number	Hits	Search Text	DB	Time stamp
-	35666	mems or mem or microelectromechanical or	USPAT;	2004/09/01 11:54
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		,
		microelectricalmechanical or (micro near2 electrical) or		
_	235	(micro near2 electrical near2 mechanical) (mems or mem or microelectromechanical or	LICDAT	2004/00/04 44-54
-	233	micromechanical or (micro near2 electro near2 mechanical)	USPAT; US-PGPUB	2004/09/01 11:54
		or (micro near2 mechanical) or microelectrical or	03-76706	
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2		
		factor\$1)		
-	204	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 11:55
,		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or	•	
		(micro near2 electrical near2 mechanical)) and (fill adj2		
		factor\$1)) and (mirror\$1 reflect\$3)		
-	150	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 11:55
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2		
_	81	factor\$1)) and (mirror\$1 reflect\$3)) and wavelength\$1 ((((mems or mem or microelectromechanical or	USPAT:	2004/09/01 11:57
	01	micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	2004/09/01 11.57
		or (micro near2 mechanical) or microelectrical or	00-1 01 08	
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2		
		factor\$1)) and (mirror\$1 reflect\$3)) and wavelength\$1) and		
		((pivot\$3 tilt\$3 rotat\$3 actuat\$3) with (mirror\$1		
,		micromirror\$1 (micro near2 mirror\$1)))		
-	37	(((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:07
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	1
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (fill adj2 factor\$1)) and (mirror\$1 reflect\$3)) and wavelength\$1) and		
		((pivot\$3 tilt\$3 rotat\$3 actuat\$3) with (mirror\$1		
		micromirror\$1 (micro near2 mirror\$1)))) and multiplex\$3		
_	73	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:10
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (high adj2 fill		
		adj2 factor)		0004/00/2
-	22	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:08
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (high adj2 fill		
		adj2 factor)) and multiplex\$3		
_	20	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:09
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (high adj2 fill		
		adj2 factor)) and multiplex\$3) and mirror\$1		
-	41	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:10
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB	
		or (micro near2 mechanical) or microelectrical or		
		microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and ((high adj2 fill		
		(micro near2 electrical near2 mechanical)) and ((nigh adj2 lill adj2 factor) same (mirror\$1 reflect\$3))	1]
		Lage ractory same (minoral reflectas))		1

-	9	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical)	USPAT; US-PGPUB	2004/09/01 12:19
		or (micro near2 mechanical) or microelectrical or	00 / 0. 05	
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and ((high adj2 fill		
		adj2 factor) same (mirror\$1 reflect\$3))) and multiplex\$3		
-	44631	mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:34
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
ļ		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT:	
		(micro near2 electrical near2 mechanical)	IBM_TDB	
-	232	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:19
}		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT:	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)	_	
-	200	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:20
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM TDB	ļ
		factor)) and (reflect\$3 mirror\$1)		
-	35188	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:21
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT:	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
-		factor)) and (reflect\$3 mirror\$1)) ((monolith\$3 (single near2	_	
		crystal)) near4 substrate\$1)		
-	14	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:21
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (reflect\$3 mirror\$1)) and ((monolith\$3 (single		
		near2 crystal)) near4 substrate\$1)		
-	10	((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 12:46
•		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
9		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (reflect\$3 mirror\$1)) and ((monolith\$3 (single		
		near2 crystal)) near4 substrate\$1)) and (multiplex\$3		
	_	wavelengths)		
-	2	6137941.pn.	USPAT;	2004/09/01 14:05
*			US-PGPUB;	
			EPO; JPO;	
]			DERWENT;	
	0000		IBM_TDB	0004/55/54 : : = =
-	9290	mirror\$1 near4 array	USPAT;	2004/09/01 14:05
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
	2042	(mirror 0.4 m and array) and (m. 1851 - 0.5 m and)	IBM_TDB	0004/00/04 44 65
-	3043	(mirror\$1 near4 array) and (multiplex\$3 wavelengths)	USPAT;	2004/09/01 14:06
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
	7.0	//maintain/AmanuAmanuAmanuAmanuAmanuAmanu	IBM_TDB	0004/02/04
-	79	((mirror\$1 near4 array) and (multiplex\$3 wavelengths)) and	USPAT;	2004/09/01 14:06
		(fill adj2 factor)	US-PGPUB;	
			EPO; JPO;	
]			DERWENT;	
L			IBM_TDB	

-	4162	(mirror\$1 near4 array) and (multiplex\$3 wavelength\$1)	USPAT; US-PGPUB; EPO; JPO;	2004/09/01 14:06
			DERWENT; IBM_TDB	
-	109	((mirror\$1 near4 array) and (multiplex\$3 wavelength\$1)) and (fill adj2 factor)	USPAT; US-PGPUB;	2004/09/01 14:35
			EPO; JPO; DERWENT; IBM_TDB	
-	92	((((mirror\$1 near4 array) and (multiplex\$3 wavelength\$1)) and (fill adj2 factor)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)	USPAT; US-PGPUB; EPO; JPO;	2004/09/01 19:00
			DERWENT;	
_	7	(US-6263123-\$ or US-6760144-\$ or US-6778728-\$).did. or	IBM_TDB USPAT;	2004/09/01 15:26
		(US-20040130774-\$ or US-20040165243-\$ or US-20030223679-\$ or US-20010026674-\$).did.	US-PGPUB	2004/00/01 10:20
-	8	(US-5965886-\$ or US-6778728-\$ or US-6760144-\$ or	USPAT;	2004/09/01 15:27
		US-6263123-\$).did. or (US-20040130774-\$ or US-20040165243-\$ or US-20030223679-\$ or US-20010026674-\$).did.	US-PGPUB	
-	7	(US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or	USPAT;	2004/09/01 15:29
		US-6760144-\$).did. or (US-20030223679-\$ or	US-PGPUB	
_	6	US-20040165243-\$ or US-20040130774-\$).did. ((US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or	USPAT;	2004/09/01 15:33
		US-6760144-\$).did. or (US-20030223679-\$ or	US-PGPUB	
		US-20040165243-\$ or US-20040130774-\$).did.) and ((((mirror\$1 near4 array) and (multiplex\$3 wavelength\$1))		
		and (fill adj2 factor)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3))		
-	7	((US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or	USPAT;	2004/09/01 16:10
		US-6760144-\$).did. or (US-20030223679-\$ or US-20040165243-\$ or US-20040130774-\$).did.) and	US-PGPUB	
	_	(multiplex\$3 wavelength\$1)		
-	7	(((US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or US-6760144-\$).did. or (US-20030223679-\$ or	USPAT; US-PGPUB;	2004/09/01 16:10
		US-20040165243-\$ or US-20040130774-\$).did.) and	EPO; JPO;	
Ì		(multiplex\$3 wavelength\$1)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)	DERWENT; IBM_TDB	
-	7	((((US-6778728-\$ or US-5965886-\$ or US-6263123-\$ or	USPAT;	2004/09/01 16:10
		US-6760144-\$).did. or (US-20030223679-\$ or US-20040165243-\$ or US-20040130774-\$).did.) and	US-PGPUB;	•
		(multiplex\$3 wavelength\$1)) and (tilt\$3 pivot\$3 rotat\$3	EPO; JPO; DERWENT;	
		actuat\$3)) and (fill adj2 factor)	IBM_TDB	0004/00/04 40 05
-	2	6657770.pn.	USPAT; US-PGPUB;	2004/09/01 16:09
			EPO; JPO;	
			DERWENT; IBM_TDB	
-	1	6657770.pn. and (multiplex\$3 wavelength\$1)	USPAT; US-PGPUB	2004/09/01 16:10
-	1	(6657770.pn. and (multiplex\$3 wavelength\$1)) and (tilt\$3	USPAT;	2004/09/01 16:10
		pivot\$3 rotat\$3 actuat\$3)	US-PGPUB; EPO; JPO;	
			DERWENT;	
		//GG57770 pp - p- d /	IBM_TDB	0004/00/04 40 45
-	0	((6657770.pn. and (multiplex\$3 wavelength\$1)) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)) and (fill adj2 factor)	USPAT; US-PGPUB;	2004/09/01 16:10
		,	EPO; JPO;	
			DERWENT; IBM_TDB	
-	4	(US-6263123-\$ or US-6760144-\$ or US-6778728-\$).did. or	USPAT;	2004/09/01 17:55
_	3	(US-20030223679-\$).did. ((US-6263123-\$ or US-6760144-\$ or US-6778728-\$).did. or	US-PGPUB	2004/00/04 49:04
		(US-20030223679-\$).did.) and (attenuat\$4 block\$3)	USPAT; US-PGPUB	2004/09/01 18:24

-	3	((US-6263123-\$ or US-6760144-\$ or US-6778728-\$).did. or	USPAT;	2004/09/01 18:24
	77	(US-20030223679-\$).did.) and (attenuat\$4 block\$3)	US-PGPUB	2004/00/04 49:42
-	′′	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:42
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO; DERWENT:	
		microelectricalmechanical or (micro near2 electrical) or		
		(micro near2 electrical near2 mechanical)) and (high adj2 fill	IBM_TDB	
	232	adj2 factor)	USPAT;	2004/09/03 10:33
-	202	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	2004/09/03 10.33
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
1		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM TDB	
		factor)	10141_100	
_	133	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:35
	100	micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	200 1100101 10:00
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT:	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (attenuat\$3 block\$3)	_ · - · · -	
-	113	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:35
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB:	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (attenuat\$3 block\$3)) and (tilt\$3 pivot\$3 rotat\$3		
		actuat\$3)	LICOAT	0004/00/04 40:07
-	38	(((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:37
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
1		microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2	DERWENT;	
1		factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3	1014-100	
		actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj		
	:	mirror\$1)) with array))		
_	82	(((mems or mem or microelectromechanical or	USPAT:	2004/09/01 18:58
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
	•	factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3		
		actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj	}	
		mirror\$1)) reflect\$4))	LIGRAT	0004/00/04 40 55
-	48	((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:55
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
	1	or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or	EPO; JPO; DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
	1	factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3	'5''-'	
		actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj		
	1	mirror\$1)) reflect\$4))) and (multiplex\$3 wavelengths		
		(wavelength near3 channels))		
-	14	(((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:42
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3		
		actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj		
		mirror\$1)) reflect\$4))) and (multiplex\$3 wavelengths		
	<u> </u>	(wavelength near3 channels))) and (high adj2 fill adj2 factor)	L	l

-	1	(((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:58
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	•
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	:
		factor)) and (attenuat\$3 block\$3)) and ((tilt\$3 pivot\$3 rotat\$3	_	
		actuat\$3) same ((mirror\$1 micromirror\$1 (micro adj		
		mirror\$1)) reflect\$4))) and (multiplex\$3 wavelengths		
		(wavelength near3 channels))) and cantilever		
-	2327	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:58
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
]	or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and cantilever	IBM TDB	
_	1230	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 18:59
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT:	
	1	(micro near2 electrical near2 mechanical)) and cantilever)	IBM_TDB	
]	and ((mirror\$1 micromirror\$1 (micro adj mirror\$1) reflect\$4))	10141_100	
	124		LISDAT:	2004/09/01 19:37
-	134	(((mems or mem or microelectromechanical or	USPAT; US-PGPUB;	2004/03/01 18.3/
		micromechanical or (micro near2 electro near2 mechanical)		
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and cantilever)	IBM_TDB	
		and ((mirror\$1 micromirror\$1 (micro adj mirror\$1) reflect\$4)))		
1		and ((attenuat\$3 block) same (wavelength\$1 channel\$1		
	404	multiplex\$3))	LICOAT	0004/00/04 40 00
-	124	((((mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:00
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
ŀ		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and cantilever)	IBM_TDB	
		and ((mirror\$1 micromirror\$1 (micro adj mirror\$1) reflect\$4)))		
		and ((attenuat\$3 block) same (wavelength\$1 channel\$1		
		multiplex\$3))) and (tilt\$3 pivot\$3 rotat\$3 actuat\$3)		
-	4226	(mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:37
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and ((attenuat\$3	IBM_TDB	
		block) same (wavelength\$1 channel\$1 multiplex\$3))		
-	91	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:38
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
	1	(micro near2 electrical near2 mechanical)) and ((attenuat\$3	IBM_TDB	
	1	block) same (wavelength\$1 channel\$1 multiplex\$3))) and		
	1	(assymetric offset) near5 (pivot\$3 tilt\$3 rotat\$3 actuat\$3 axis		
	1	axes)		
-	91	((mems or mem or microelectromechanical or	USPAT;	2004/09/01 19:38
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
	1	or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
	1	microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
	1	(micro near2 electrical near2 mechanical)) and ((attenuat\$3	IBM_TDB	
1		block) same (wavelength\$1 channel\$1 multiplex\$3))) and	_	
		((assymetric\$2 offset) near5 (pivot\$3 tilt\$3 rotat\$3		
1	!	axis axes))	1	
-	233	(mems or mem or microelectromechanical or	USPAT;	2004/09/03 10:33
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
1		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)		
	·	1/	L	

-	135	((mems or mem or microelectromechanical or	USPAT;	2004/09/03 10:34
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
	-	or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
}		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (multiplex\$4 wavelengths channels)	_	
-	66	(((mems or mem or microelectromechanical or	USPAT;	2004/09/03 10:35
		micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB;	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
	ł	microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (multiplex\$4 wavelengths channels)) and	15155	
		(attenat\$3 block\$3)		,
_	1	((((mems or mem or microelectromechanical or	USPAT;	2004/09/03 10:42
	'	micromechanical or (micro near2 electro near2 mechanical)	US-PGPUB:	2004/03/03 10.42
			ł '	
		or (micro near2 mechanical) or microelectrical or	EPO; JPO;	
		microelectricalmechanical or (micro near2 electrical) or	DERWENT;	
		(micro near2 electrical near2 mechanical)) and (fill adj2	IBM_TDB	
		factor)) and (multiplex\$4 wavelengths channels)) and		
		(attenat\$3 block\$3)) and (electrode with potential with mirror)		
-	0	(mirror with (landing) with electrode with potential) and	USPAT;	2004/09/03 10:43
		attenuat\$3	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
	-		IBM_TDB	
-	20	mirror with (landing) with electrode with potential	USPAT;	2004/09/03 10:47
			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	4	(mirror with (landing) with electrode with potential) and	USPAT;	2004/09/03 10:45
		multiplex\$3	US-PGPUB;	
		•	EPO; JPO;	
	1		DERWENT;	
			IBM_TDB	
_	41	mirror with electrode with ("same" near3 potential)	USPAT;	2004/09/03 10:47
		,	US-PGPUB:	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	5	(mirror with electrode with ("same" near3 potential)) and	USPAT;	2004/09/03 10:48
		attenuat\$3	US-PGPUB;	2004/00/00 10.40
			EPO; JPO;	
]		DERWENT;	
	j		IBM TDB	
_	5	((mirror with electrode with ("same" near3 potential)) and	USPAT;	2004/09/03 10:56
_	1	attenuat\$3) not ((mirror with (landing) with electrode with	US-PGPUB;	2004/09/03 10.30
		attenualss) not ((mirror with (landing) with electrode with potential) and multiplex\$3)	EPO; JPO;	
		Potential) and multiplex#3)		:
]		DERWENT;	
	24000	mom or mome	IBM_TDB	2004/00/02 40:50
-	34969	mem or mems	USPAT;	2004/09/03 10:56
	1		US-PGPUB;	
]			EPO; JPO;	
			DERWENT;	•
			IBM_TDB	
-	1746	(mem or mems) and (circuit near5 substrate)	USPAT;	2004/09/03 10:57
• 0			US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	24	(mem or mems) and (fabricate near3 circuit near5 substrate)	USPAT;	2004/09/03 10:58
	1	· ·	US-PGPUB;	
_			EPO; JPO;	1
			DERWENT;	
			IBM_TDB	
				

-	0	((mem or mems) and (fabricate near3 circuit near5	USPAT;	2004/09/03 10:58
		substrate)) and attenuat\$3	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	3	((mem or mems) and (fabricate near3 circuit near5	USPAT;	2004/09/03 11:08
		substrate)) and multiplex	US-PGPUB;	
		,,	EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	27364	wavelength near3 multiplex\$3	USPAT;	2004/09/03 11:08
		3	US-PGPUB:	
			EPO; JPO;	
			DERWENT:	
			IBM_TDB	
	963	(wavelength near3 multiplex\$3) and ((mirror micromirror	USPAT;	2004/09/03 11:10
-	903	(micro near2 mirror\$1)) with (tilt\$3 rotat\$3 pivot\$3))	US-PGPUB;	2004/09/03 11.10
		(micro near2 mirrors r)) with (miss rotats spivotss))		
			EPO; JPO;	
1			DERWENT;	
			IBM_TDB	
-	0	((wavelength near3 multiplex\$3) and ((mirror micromirror	USPAT;	2004/09/03 11:10
		(micro near2 mirror\$1)) with (tilt\$3 rotat\$3 pivot\$3))) and	US-PGPUB;	
		((rotat\$3 tilt\$3 pivot\$3) with (center near4 gravity))	EPO; JPO;	
			DERWENT;	
			IBM_TDB	
-	15	(wavelength near3 multiplex\$3) and ((off near3 center) with	USPAT;	2004/09/03 11:10
		(tilt\$3 rotat\$3 pivot\$3))	US-PGPUB;	
			EPO; JPO;	
			DERWENT;	
			IBM TDB	
-	1	(US-20020135864-\$).did.	US-PGPUB	2004/09/03 11:14
-	8	(US-6760144-\$ or US-6778728-\$ or US-5965886-\$ or	USPAT;	2004/09/03 14:09
		US-6263123-\$).did. or (US-20030112507-\$ or	US-PGPUB	
		US-20030223679-\$ or US-20040125361-\$ or		
		US-20020135864-\$).did.		
_	1	((US-6760144-\$ or US-6778728-\$ or US-5965886-\$ or	USPAT;	2004/09/03 11:16
		US-6263123-\$).did. or (US-20030112507-\$ or	US-PGPUB	200 1100/00 11110
		US-20030223679-\$ or US-20040125361-\$ or	0010100	
		US-20020135864-\$).did.) and (polish\$3 near4 mirror)		
1_	1	((US-6760144-\$ or US-6778728-\$ or US-5965886-\$ or	USPAT;	2004/09/03 11:16
-	'	US-6263123-\$).did. or (US-20030112507-\$ or	US-PGPUB	230-700/00 11.10
		US-20030223679-\$ or US-20040125361-\$ or	JO-1 GF 0B	
	1	US-20020135864-\$).did.) and (polish\$3 near4 mirror)		
	4693	(359/214,224,291,290,295,298) (385/15,18) (310/309)).ccls.	LISDAT	2004/09/03 14:10
-	4093	((333)214,224,231,230,233,230) (363) 13, 16) (310/309)).CCIS.	USPAT;	2004/03/03 14.10
	1155	(((350/214 224 201 200 205 200) /205/45 40)	US-PGPUB	2004/00/02 44:40
-	1155	(((359/214,224,291,290,295,298) (385/15,18)	USPAT;	2004/09/03 14:10
	1	(310/309)).ccls.) and mem\$1	US-PGPUB	2004/00/02 44:42
-	1	((((359/214,224,291,290,295,298) (385/15,18)	USPAT;	2004/09/03 14:10
		(310/309)).ccls.) and mem\$1) and wavlength\$1	US-PGPUB	0004/00/00 11 15
-	710	((((359/214,224,291,290,295,298) (385/15,18)	USPAT;	2004/09/03 14:10
		(310/309)).ccls.) and mem\$1) and wavelength\$1	US-PGPUB	
-	386	((((((359/214,224,291,290,295,298) (385/15,18)	USPAT;	2004/09/03 14:11
		(310/309)).ccls.) and mem\$1) and wavelength\$1) and	US-PGPUB	
	1	((mirror\$1 micromirror\$1) with (tilt\$3 rotat\$3 pivot\$3))		